IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No	10/728,532
Confirmation No.	
Filing Date	December 5, 2003
Inventor	John F. Van Itallie et al.
Assignee	Micron Technology, Inc.
Group Art Unit	
Examiner	Kathleen Duda
Attorney's Docket No	Ml22-2458
Customer No	021567
Title: Photolithographic Methods Of Using A Single Reticle To Form Overlapping Patterns	

RESPONSE TO JUNE 1, 2006 FINAL OFFICE ACTION

Response Filed After Final Action

To:

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Commissioner for Patents

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AMENDMENTS